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July 7, 2004

Mail Stop AF Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

Re:

Applicant(s):

Woo Sik Yoo

Assignee:

WaferMasters, Inc.

Title:

Method Of Forming An Oxide Layer (As Amended)

Serial No.:

10/085,498

Examiner:

Kirsten Jolley

Filed: February 26, 2002

Docket No.:

M-11549 US

Group Art Unit: 1762

Dear Sir:

Transmitted herewith are the following documents in the above-identified application:

- (1) Certification of Facsimile Transmission;
- (2) This Transmittal Letter (in duplicate);
- (3) Response to Final Office Action (10 pages); and
- (4) Petition for Extension of Time.

 $\boxtimes$ No additional fee is required.

The fee has been calculated as shown below:

#### CLAIMS AS AMENDED

m . 101:	Claims Remaining After Amendment		Highest No. Previously Paid For		Present Extra		Rate	_	Additional <u>Fee</u>	
Total Claims	19	Minus	31	-	0	х	\$18.00	\$		0
Independent Claims	2	Minus	5	=	0	x	\$84.00	\$		0
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	arge any additional fe t No. 50-2257	es required	and credit any	overpa	yment to c	ur E	eposit	•		
						1	otal:	\$	<u>55.00</u>	

Certification of Facsimile Transmission

I hereby certify that this paper is being facsimile transmitted to the U.S. Patent and Trademetik Office on the date shown below.

Ma Kavanaugh

<u>July 7, 2004</u>

Respectfully submitted,

David S. Park

Attorney for Applicants

Reg. No. 52,094

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David S. Park

Reg. No. 52,094

Attorney for Applicants

PAGE 3/14 \* RCVD AT 7/7/2004 5:33:11 PM [Eastern Daylight Time] \* SVR:USPTO-EFXRF-1/1 \* DNIS:8729306 \* CSID:9497527049 \* DURATION (mm-ss):05-28

July 7, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

9497527049

Applicant(s):

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Jolley, Kirsten

Group Art Unit:

1762

Docket No.:

M-11549 US

Confirmation No.

8701

Irvine, California July 7, 2004

### RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Final Office Action dated April 6, 2004, Applicant submits the following amendments and remarks. A one-month extension of time, extending the period for response to August 6, 2004, is requested in an accompanying petition.